

FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)				Attorney Docket Number 5347-204		Serial No. not yet assigned	
				Applicants: Daniel J. C. Hill, et al.			
				Filing Date concurrently herewith		Group 1756	
U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
	1	11-329944	11/30/99	IPO (Abstract in English)	H01L	21/027	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	2.	J.C.H. Spence et al; Low Energy Point Reflection Electron Microscopy, Surface Review and Letters, Vol. 4, No. 3 (1997) pp 577-587.					
	3.	J.C.H. Spence et al; On the reconstruction of low voltage point projection holograms, Electron Holography, (1995) pp 267-276.					
	4.	Hans-Werner Fink et al; State of the Art Low-Energy Electron Holography, Electron Holography (1995) pp 257-266.					
	5.	J.C.H. Spence et al; Electron Holography at Low Energy, Introduction to Electron Holography, pp 311-331.					
	6.	D.C. Joy et al; Advanced SEM Imaging, Characterization and Metrology for ULSI Technology; 1998 International Conference, pp 653-666.					
	7.	Russell Young et al; The Topografiner: An Instrument for Measuring Surface Microtopography, Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011.					
	8.	Werner Veith et al; Point Projector Electron Microscope, Phy. Rev. Vol. 56, 705 (1939).					


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Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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FORM PTO-1449 U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5347-204		Serial No. 09/781,881	
LIST OF DOCUMENTS CITED BY APPLICANT (Use several sheets if necessary)				<div style="font-size: 2em; font-weight: bold; transform: rotate(-5deg);">RECEIVED</div> <div style="font-size: 1.2em; font-weight: bold; transform: rotate(-5deg);">JUN 14 2001</div>			
				Applicants: Daniel J. C. Herrera			
				Filing Date February 12, 2001		Group 1645	
U. S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation Yes No
W	1	11-329944	11/30/99	JPO (Abstract in English)	H01L	21/027	
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W	2.	J.C.H. Spence et al; <i>Low Energy Point Reflection Electron Microscopy</i> , Surface Review and Letters, Vol. 4, No. 3 (1997) pp 577-587.					
W	3.	J.C.H. Spence et al; <i>On the reconstruction of low voltage point projection holograms</i> , Electron Holography, (1995) pp 267-276.					
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W	7.	Russell Young et al; <i>The Topografiner: An Instrument for Measuring Surface Microtopography</i> , Review of Scientific Instruments, Volume 43, Number 7, (July 1972) pp 999-1011.					
W	8.	G. Morton Werner Veith et al; <i>Point Projector Electron Microscope</i> , Phy. Rev. Vol. 56, 705 (1939).					

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Substitute form 1449A/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number		09/781,881	
		Filing Date		February 12, 2001	
		First Named Inventor		Daniel J. C. Herr	
		Group Art Unit		1645	
		Examiner Name		not yet assigned	
Sheet	1	of	1	Attorney Docket Number	5347-204

U.S. PATENT DOCUMENTS							
Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Number	Kind Code (if known)				
uv	1.	5,455,850		Howells et al;	10/03/1995	378/34	
FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No.	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T
		Office	Number				
uv	2.		JP 09 016062A	Patent Abstracts of Japan	01/17/1997		
OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS							
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published					
uv	3.	E. Hecht: "Optics" 1987, Addison-Wesley XP002184727, page 593-596					
uv	4.	Anonymous: "Wafer Conformable Mask Image", Research Disclosure (December 1984) page 609 XP002184726.					
uv	5.	C. Jacobsen et al; "Projection X-Ray Lithography Using Computer-Generated Holograms: A study of compatibility with proximity lithography"; Journal of Vacuum Science and Technology: Part B, Am Inst. of Physics. New York, US vol. 10. No. 6 (11/1/1992) pgs 3177-3181 XP000332529					
uv	6.	C. Jacobsen et al; "X-Ray Holographic Microscopy Using Photoresists", Journal of the Optical Society of America - A, Optical Society of America, Wash. US. vol. 7, no 10 (10/1/1990) pgs 1847-1861 XP000163095.					

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Examiner Signature		Date Considered	1/27/02
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